

Samenvatting NANOMEFOS

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Henselmans, Rens, 'Design, Realization and Testing of NANOMEFOS, Mikroniek, 2008 nr. 5

Cacace, L.A., 'An Optical Distance Sensor: Tilt robust differential confocal measurement with mm range and nm uncertainty', PhD Thesis, Technische Universiteit Eindhoven, to be published in 2009

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